



566.41191X00

THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Y. KURATA, et al.

Serial No.: 10/049,672

35 USC 371 Date: APRIL 30, 2002

Title: POLISHING MEDIUM FOR CHEMICAL-MECHANICAL
POLISHING, AND METHOD OF POLISHING SUBSTRATE
MEMBER

Group AU: 1765

Examiner: Duy Vu Nguyen Deo

Confirm. No: 7706

SUBMISSION UNDER 37 CFR 1.114
(AMENDMENT)

Mail Stop: RCE

Commissioner for Patents

P.O. Box 1450

Alexandria, Virginia 22313-1450

October 23, 2006

Sir:

In response to the Office Action dated April 24, 2006, concurrently with the filing of a Request for Continued Examination (RCE) Transmittal, and as the necessary Submission therefor, the period for response having been extended for three (3) months by the attached Petition for Extension of Time, please amend the above-identified application as listed in the following, and as set forth on the following pages:

AMENDMENTS TO THE CLAIMS; and

REMARKS are included following the amendments.